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| Form PTO-1449 (Rev. 8-88) | Attorney Docket No. ILL02-023-DIV-US | Serial No. 10/670,585 |
| INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) | Applicant: Chang Liu, et al. | |
| | Filing Date: September 25, 2003 | Group: 2881 |


| Examiner Initial* | OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS | |
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| | Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages | |
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| Examiner <i>James J. Thompson</i> | Date Considered <i>5/20/05</i> |
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James P. Hyslop 5/20/05

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| <i>9/2</i> | B1 | 5,883,387 | 03/1999 | | | | |
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| | | | | | | | Yes | No |
| <i>9/2</i> | B3 | EP 0786642 | 07/1997 | EP | | | | |
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| <i>9/2</i> | B6 | International Search Report for application no. PCT/US2004/015161 dated October 27, 2004. | |

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| Examiner <i>James J. Lyfman</i> | Date Considered <i>5/20/05</i> |
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